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Edwards STP-iXR1606 Technical Specifications

Inlet flange size	VG200/ VG250 ISO200F/ ISO250F ICF253/ ICF305	VG150 ISO160F ICF203	
Backing port size	KF40		
Pumping speed N ₂	1600	1000	Litres/second
Pumping speed H ₂	1200	800	Litres/second
Compression ratio N ₂ /H ₂	>10 ⁸ / 1x10 ³		
Ultimate pressure	10 ⁻⁷ (10 ⁻⁹)		Pa (Torr)
Allowable backing pressure	266 (2)		Pa (Torr)
Max gas flow N ₂ * ¹ (water cooled only)	4700 (7.94)		sccm (Pa m ³ /sec)
Max gas flow Ar * ¹ (water cooled only)	1800 (3.04)		sccm (Pa m ³ /sec)
Rated speed	36,500		rpm
Starting time	<8		minutes
Mounting position	Any orientation		
Input voltage	200-240		V
Max input power	750		VA
Weight	48		kg

**1: The maximum gas flow value applies for N₂ or Ar gas pumped continuously, with water cooling temperature under 25 degree C and a backing pump of 10,000 l/min size or larger used. The value is changed if operated under different conditions*



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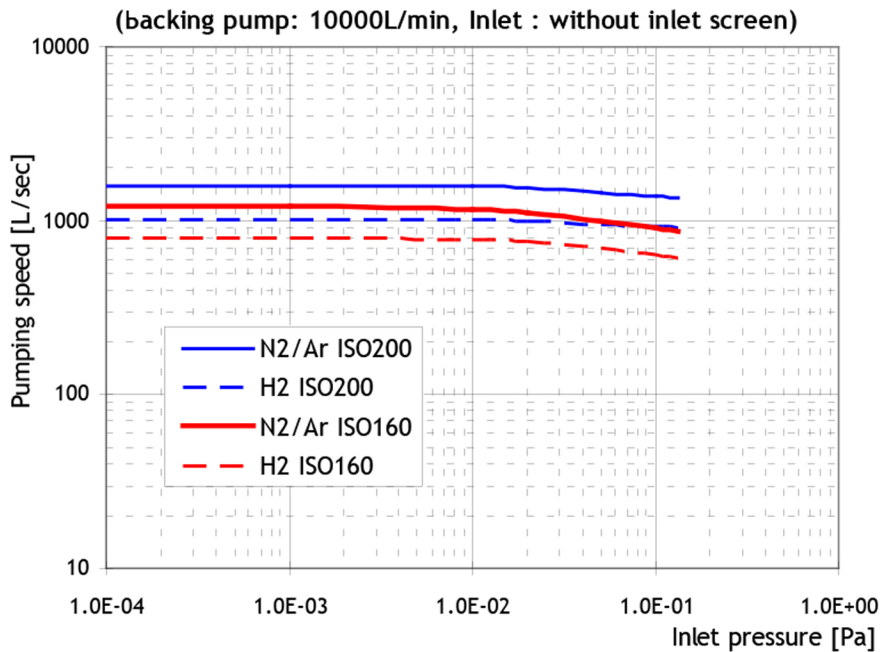
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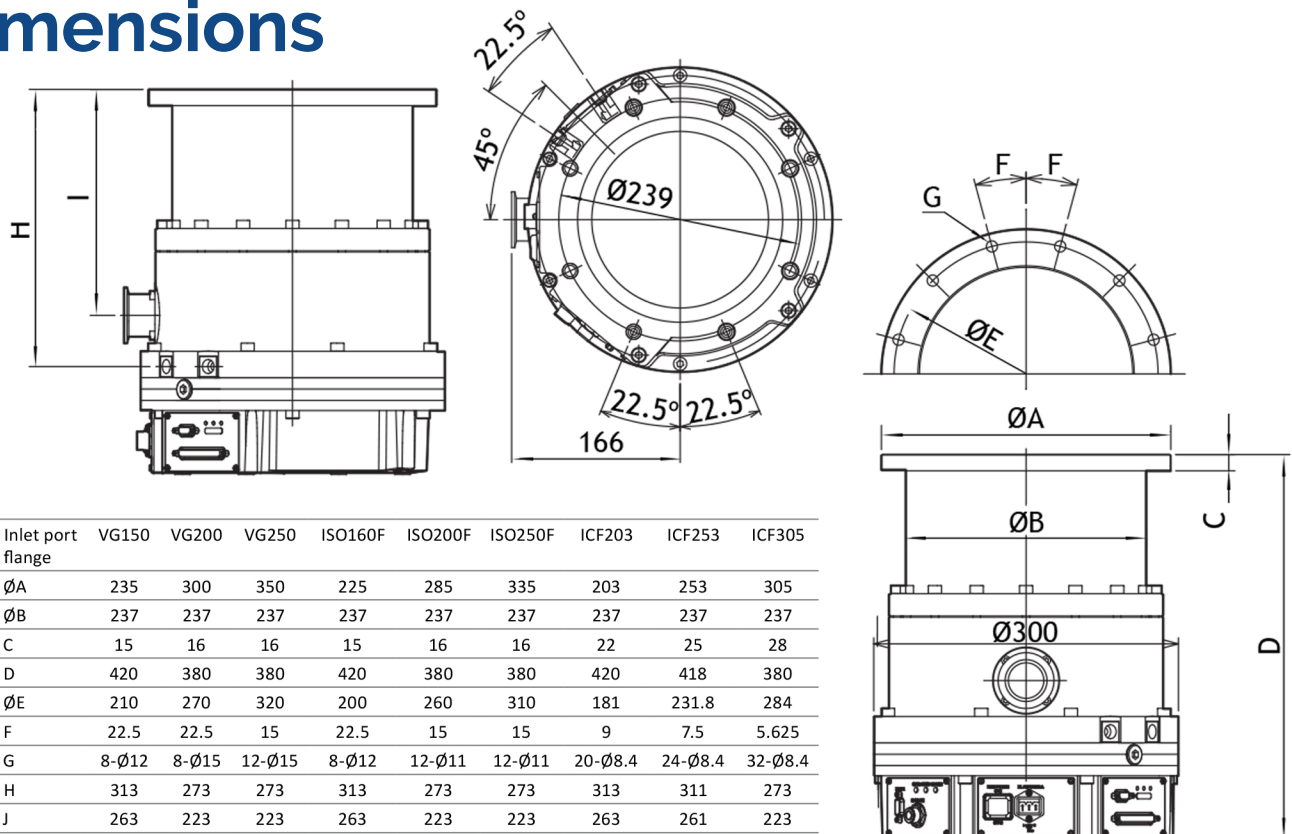
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Edwards STP-iXR1606 Pumping Curves



Dimensions





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Features & Benefits

- revolutionary, newly developed rotor design
- compact design makes for easy installation & small footprint
- fully integrated onboard controller
- energy saving - 32% reduced power consumption in high gas flow area
- highest pumping speed in the 8" TMP class
- corrosion resistant model available

Applications

- plasma etch • ECR etch • film deposition • sputtering • ion implantation source • beam line pumping end station • MBE • diffusion • photo resist stripping • crystal, epitaxial growth • wafer inspection • load lock chambers • surface analysis • mass spectrometry • electron microscopy • high energy physics • radioactive applications

